

Temperature-Dependent RF Small-Signal and Noise Characteristics of SOI Dynamic Threshold Voltage MOSFETs

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Abstract—In this paper, temperature-dependent RF small-signal and noise characteristics of silicon-on-insulator (SOI) dynamic threshold voltage (DT) MOSFETs are experimentally examined. In the low-voltage regime, both the cutoff and maximum oscillation frequencies (f_t and f_{max}) tend to increase with temperature. In addition, the inherent body-related parasitics and the series resistance have much more impact on f_{max} than f_t . Besides, we found that the noise stemmed from the body resistance (R_b) would contribute to the output noise current, and degrade the minimum noise figure (NF_{min}). Our study may provide insights for RF circuit design using advanced SOI DT MOSFETs.

Index Terms—Body resistance, dynamic threshold voltage (DT) MOSFETs, noise, RF, silicon-on-insulator (SOI), small signal, temperature dependence.

I. INTRODUCTION

DU TO its larger current driving ability with low leakage current, the dynamic threshold voltage (DT) MOSFET is attractive for low-power applications [1]. Hence, the dc characteristics and modeling of the DT MOSFET have been widely studied since its introduction [2]–[4]. Moreover, the temperature effect on its dc characteristic has also been well investigated [4].

Several optimized silicon-on-insulator (SOI)- or bulk-based DT MOS fabrication processes with improved performance have been demonstrated [5], [6], and its ability of RF applications with high cutoff frequency (f_t) and maximum oscillation frequency (f_{max}) has been reported as well [7]–[9]. However, the temperature effect on the RF characteristics of DT MOSFETs is rarely known.

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To avoid a large leakage current flowing through the source–body junction, a DT MOSFET is usually biased in the low gate overdrive (V_{GT}) region. Therefore, it is crucial to examine the RF small-signal and noise characteristics under this regime.

This paper is an experimental investigation on the RF small-signal and noise characteristics of SOI DT MOSFETs and is organized as follows. The measurement environment and device structures/geometries are described in Section II. In Section III, the temperature effect of body-related parasitics and series resistances on f_t and f_{max} will then be investigated. In Section IV, the RF noise behavior and its temperature dependence will be discussed for the first time. The temperature dependences of the equivalent thermal resistance and minimum noise figure will be examined as well. Finally, conclusions will be drawn in Section V.

II. DEVICES AND EXPERIMENTS

The RF SOI DT MOSFETs used in this work were fabricated using UMC 65-nm SOI technology. These RF devices were laid out in the multifinger (eight fingers) and multigroup (16 groups) structure with 1- μm channel width per finger.

On-wafer two-port common-source high-frequency S and noise parameters were measured using an ATN NP5B noise measurement system with Cascade microwave probes. Besides, to eliminate the inevitable parasitic accompanied with the probing pads, the S -parameters of the devices' corresponding dummy were measured and then used to perform the S and noise parameters' de-embedding procedure.

Fig. 1 shows the temperature dependences of threshold voltage (V_T) extracted by the constant current ($I_{th} \equiv 50 \text{ nA} \times W/L$) method. Due to the negative temperature coefficient of the device's Fermi potential [4], V_T exhibits the negative temperature dependence for each channel length device.

The equivalent circuit for both RF small-signal and noise behaviors is depicted in Fig. 2. The inherent body-related parasitics include the source- and drain-side junction capacitances ($C_{j, sb}$ and $C_{j, db}$, respectively), the junction resistance ($R_{j, sb}$), the body resistance (R_b), and the body-transconductance (g_{mb}). The series resistances R_s , R_d , and R_g were determined using the proposed zero method [10], and the other parameters along with the channel noise current \bar{i}_d can be extracted by the extraction method presented in [11]. Note that to keep the device

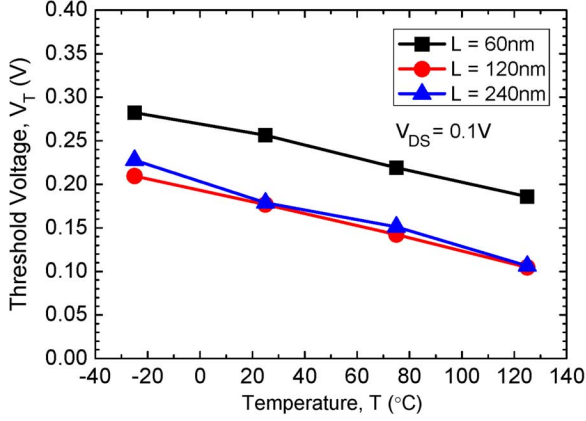


Fig. 1. Temperature dependence of the threshold voltage for SOI DT MOSFETs.

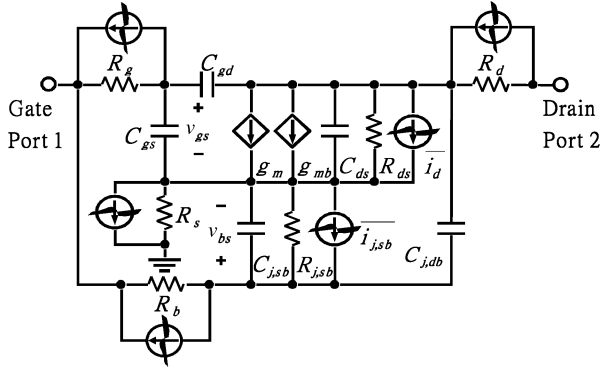


Fig. 2. RF small-signal and noise equivalent circuit for the SOI DT MOSFET.

operating in the saturation region, we let $V_{GS}(=V_{BS}) = V_{DS} \equiv VDD$ in our experiments.

III. RF SMALL-SIGNAL CHARACTERIZATION

The cutoff frequency (f_t) and maximum oscillation frequency (f_{max}) are two common figures of merit used to characterize the RF performance of a device. Based on the equivalent circuit shown in Fig. 2 and neglecting the series resistances R_s , R_d , and R_g , the “intrinsic” f_t and f_{max} for the DT MOSFET biased in the low VDD regime can be approximately expressed as the following [12]:

$$f_t \approx \frac{g_m}{2\pi\sqrt{C_{gs}(C_{gs} + 2C_{gd})}} \approx \frac{g_m}{2\pi C_{gs}} \quad (1)$$

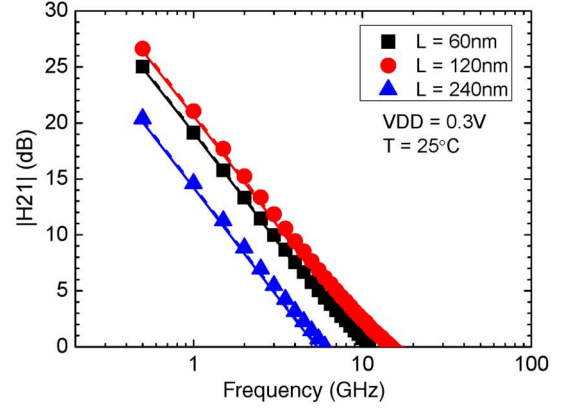
$$f_{max} \approx f_{max0} \left\{ 1 + g_{mb}R_{ds} \frac{C_{j,db}}{C_j} \right\}^{-0.5} \equiv f_{max0} \cdot \alpha_{DT} \quad (2)$$

In (1) and (2), $C_j = C_{j,sb} + C_{j,db}$,

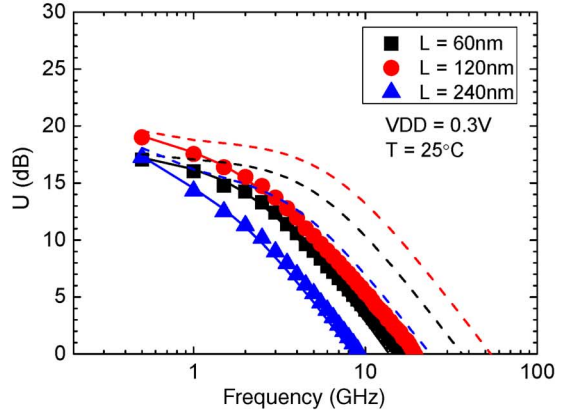
$$\alpha_{DT} = \left\{ 1 + g_{mb}R_{ds} \frac{C_{j,db}}{C_j} \right\}^{-0.5} \quad (3)$$

and

$$f_{max0} \approx \frac{f_t}{2} \sqrt{\frac{R_{ds}}{R_i}} \quad (4)$$



(a)



(b)

Fig. 3. (a) Short-circuit current gain $|H_{21}|$ and (b) unilateral power gain U with and without considering the series resistance effect (symbols: measured data; solid and dash lines: modeled results with and without considering the series resistance effect, respectively).

where R_i is the input resistance, which can be extracted by optimizing $\text{Re}(Z_{11})$.

The approximation in (1) and (2) holds in the low VDD regime, where $g_m/g_{mb} \gg 1$, $R_b/R_i \gg 1$, $g_{mb}R_b \gg C_{j,db}/C_j$, and $\omega R_b C_j \gg 1$ around f_{max} .

Equation (1) implies that the inherent body-related parasitics of the DT MOSFET would have little influence on f_t . In the low VDD regime, since g_m tends to increase with temperature [4], [13], f_t would have a positive temperature coefficient. On the other hand, due to the less temperature-dependent behavior of $\sqrt{R_{ds}/R_i}$ and the degradation factor α_{DT} , f_{max} tends to have the same temperature dependence as f_t [12]. That is, in the low VDD regime, both intrinsic f_{max} and f_t would increase with temperature.

To investigate the overall performance, however, the impact of the series resistance effect on f_{max} and f_t should be examined. Fig. 3 shows that the series resistance has much more significant effect on the unilateral power gain U (involved in the determination of f_{max}) than the short-circuit current gain $|H_{21}|$ (involved in the determination of f_t) at $VDD = 0.3$ V. Compared to the series resistances, the much larger input and output impedance in the low VDD regime would dominate $|H_{21}|$, and hence, f_t . The little series resistance effect on f_t can be also deduced from Fig. 4(a) and (b), where f_t has nearly the same temperature coefficient as g_m for each channel length device.

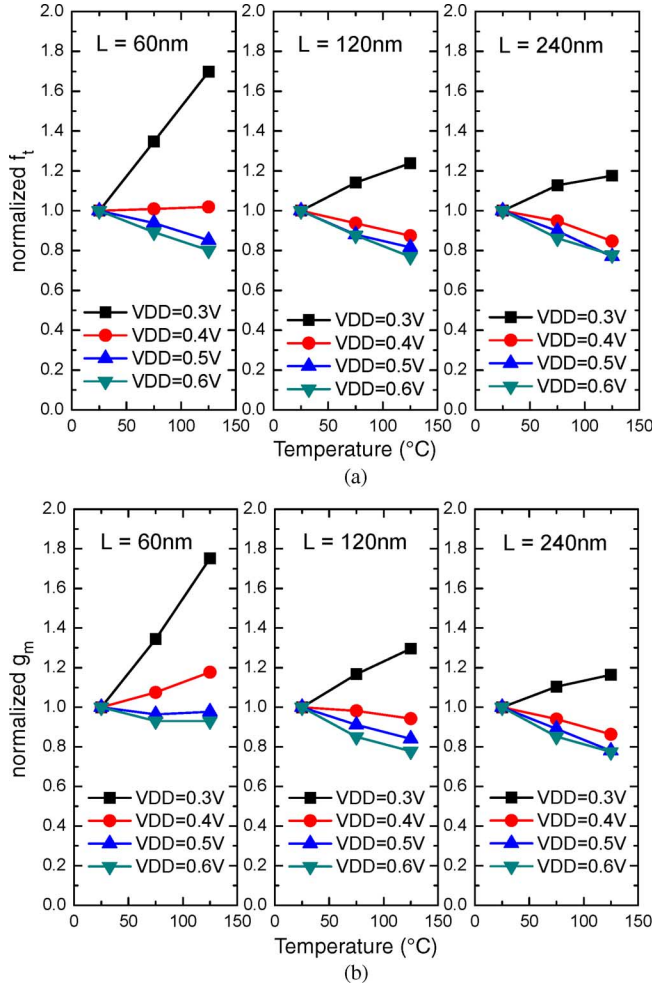


Fig. 4. Temperature dependences for: (a) f_t and (b) g_m . (Data normalized with respect to their corresponding values at $T = 25^\circ\text{C}$.)

This coincides with the implication in (1), which has assumed the series resistance is insignificant.

The input and output impedance matching for the maximum available power gain, and hence, f_{\max} , however, can be greatly influenced by the series resistances. Moreover, since the degradation factor α_{DT} is found to be nearly temperature independent for each channel length device, as shown in Fig. 5(a), the degraded temperature dependence of f_{\max} , shown in Fig. 5(b), would be mostly caused by the series resistance effect. That is, the larger resistances at higher temperatures would severely degrade f_{\max} .

IV. RF NOISE CHARACTERIZATION

A. Channel Noise and Equivalent Thermal Resistance

The extracted power spectral density for the channel noise current \bar{i}_{d} (denoted as S_{id}) is shown in Fig. 6, and is usually expressed as follows [14]:

$$S_{id} = 4k_B T \gamma g_{d0} \quad (5)$$

where $k_B \approx 1.38 \times 10^{-23}$ J/K is the Boltzmann constant, T is the ambient temperature in kelvin, g_{d0} is the channel conductance at zero drain-source voltage, and γ is the noise factor.

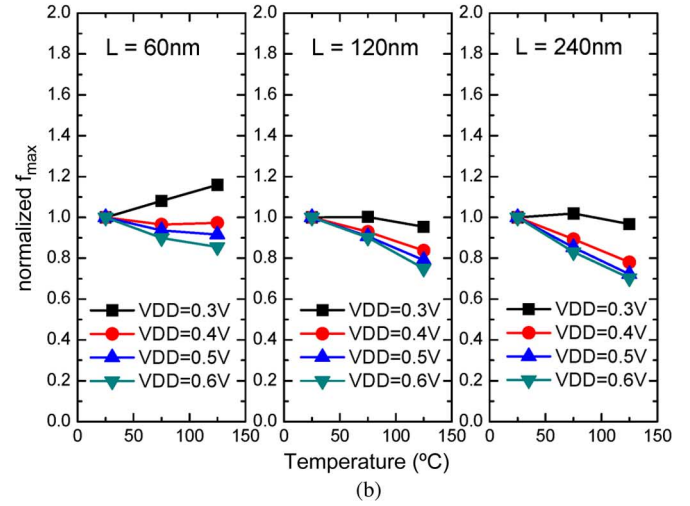
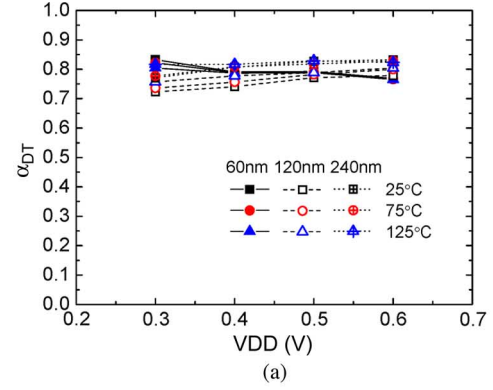


Fig. 5. Temperature dependences for: (a) α_{DT} and (b) f_{\max} . (Data normalized with respect to their corresponding values at $T = 25^\circ\text{C}$.)

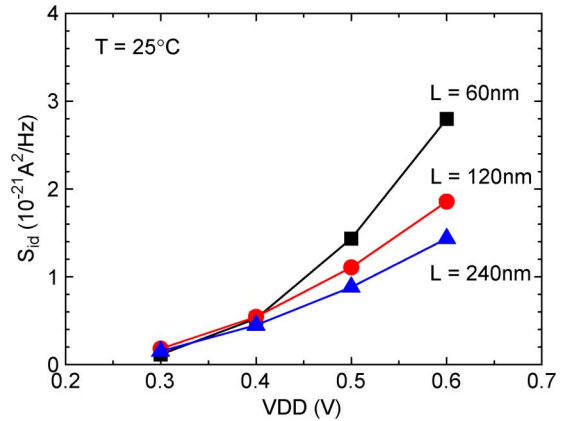


Fig. 6. Channel noise versus VDD.

Besides, [15] has shown that γ has a weak temperature dependence, and the temperature dependence of S_{id} is dominated by that of g_{d0} and T .

Fig. 7(a) and (b), respectively, shows the temperature dependences of S_{id} and g_{d0} . In the low VDD regime, since g_{d0} tends to increase with temperature [12], S_{id} would increase accordingly as predicted by (5). Note that (5) was originally derived for the device operating in the strong inversion region. However,

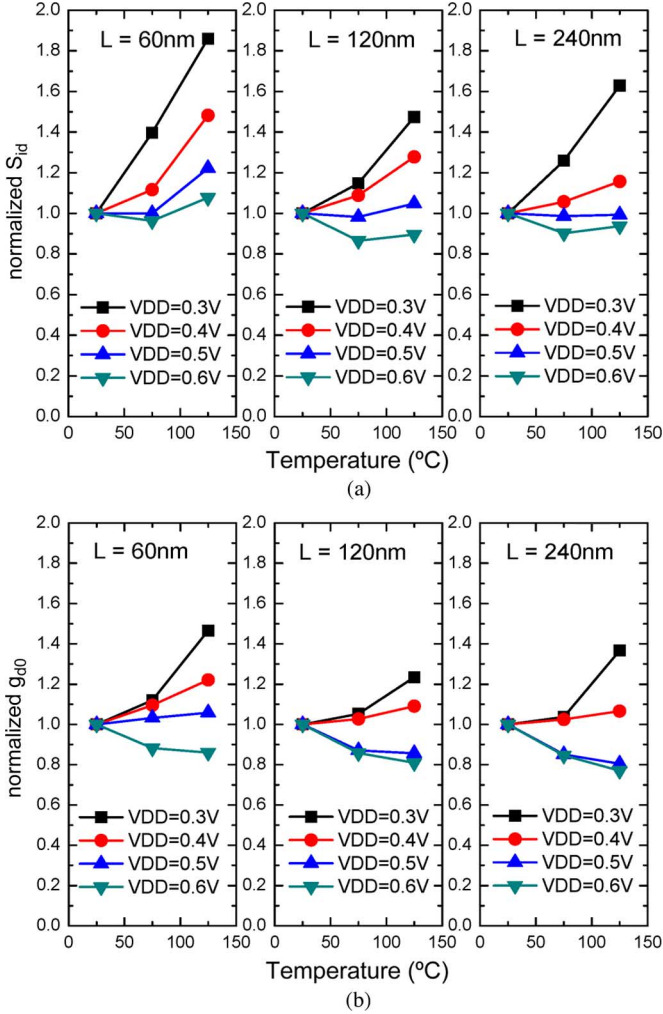


Fig. 7. Temperature dependences for: (a) S_{id} and (b) g_{d0} . (Data normalized with respect to their corresponding values at $T = 25^\circ\text{C}$.)

in our experiments, the consistent prediction results for the temperature dependence of S_{id} shows that it seems to remain valid even for the medium or weak inversion applications.

The channel noise has a significant effect on the equivalent thermal resistance R_n for conventional MOSFETs. In fact, by neglecting the body trans-conductance, R_n for DT MOSFETs would be approximately the same as that for conventional MOSFETs as expressed in the following:

$$R_n \approx \frac{S_{id}}{4k_B T_0 g_m^2} + \frac{T}{T_0} R_g \quad (6)$$

where $T_0 = 290\text{ K}$ is the reference temperature. Note that (6) indicates that in the low VDD regime, the body-related parasitics would have little influence on R_n .

Fig. 8(a) shows R_n versus temperature curves for each channel length device. Since V_T for $L = 60\text{ nm}$ device is about 0.1 V higher than those for $L = 120\text{ nm}$ and $L = 240\text{ nm}$ devices in the whole temperature range (see Fig. 1), we first consider $VDD = 0.3\text{ V}$ for $L = 120\text{ nm}$ and $L = 240\text{ nm}$ devices, and $VDD = 0.4\text{ V}$ for the $L = 60\text{ nm}$ device to keep approximately the same gate overdrive voltage. In this case, one can compare the temperature dependence for S_{id} in

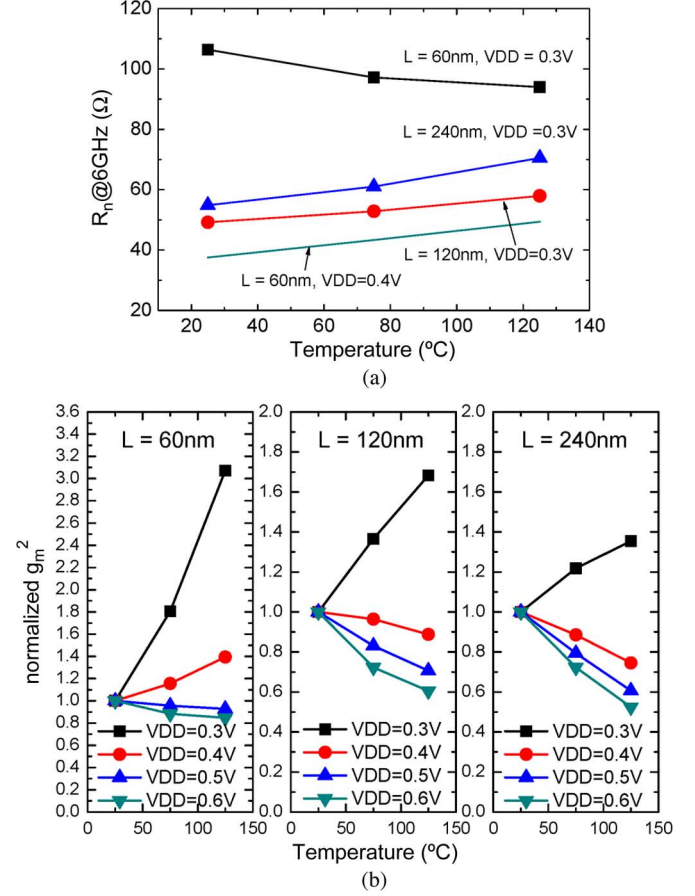


Fig. 8. Temperature dependences for: (a) R_n and (b) g_m^2 . (Data normalized with respect to their corresponding values at $T = 25^\circ\text{C}$.)

Fig. 7(a) and that for g_m^2 in Fig. 8(b). Since S_{id} tends to have the similar temperature coefficient as g_m^2 , according to (6), R_n tends to increase with temperature mainly due to the increase of R_g and T .

For an $L = 60\text{ nm}$ device operating at weaker bias condition, i.e., $VDD = 0.3\text{ V}$; however, g_m^2 tends to more deeply increase with increasing temperature than S_{id} . This could compete with or even overwhelm the contribution from “hot” R_g . Therefore, R_n tends to decrease with increasing temperature. This also shows the existence of the zero temperature coefficient for R_n , which occurs between $VDD = 0.3\text{ V}$ and $VDD = 0.4\text{ V}$ for the $L = 60\text{ nm}$ device.

B. Output Noise Current and Minimum Noise Figure

Unlike R_n , the minimum noise figure NF_{\min} may be strongly influenced by R_b . Although the analytical expression for NF_{\min} is not easily derived, the noise contribution arising from R_b to the output noise current flowing into the drain terminal can be analyzed and regarded as an important factor determining NF_{\min} .

The noise power spectral density arising from R_b (denoted as S_{iRb}) is considered as thermal noise, and can be expressed as follows:

$$S_{iRb} = 4k_B T / R_b. \quad (7)$$

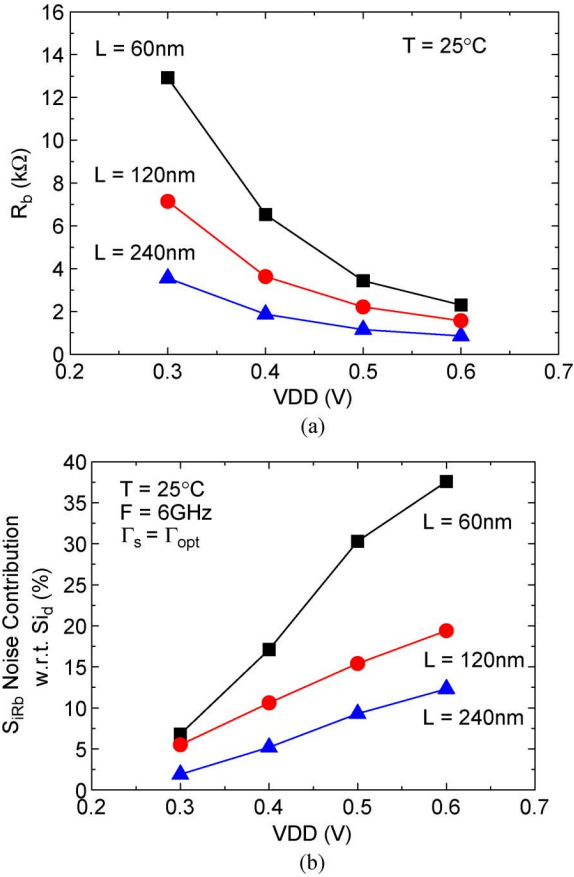


Fig. 9. (a) Extracted body resistance as a function of VDD . (b) Noise contribution from the body noise S_{iRb} to the output noise current with respect to that from the channel noise.

The extracted R_b values and their corresponding S_{iRb} contribution with respect to S_{id} counterpart to the output noise current and are shown in Fig. 9(a) and (b), respectively. We found that larger R_b in the low VDD regime would have less S_{iRb} noise contribution for each length device. This figure also shows that the shorter device with larger R_b would have more S_{iRb} contribution. It is worth noting that the smaller body cross-sectional area seen in the direction perpendicular to the channel current flow can account for the larger R_b present in the shorter device.

Through the sensitivity analysis of the variation of R_b to its noise contribution, as shown in Fig. 10, we can see that its noise contribution could be reduced with increasing R_b . In fact, the noise equivalent circuit for DT MOSFETs would be equivalent to that for conventional MOSFETs when R_b approaches infinity and can be removed in the equivalent circuit. Therefore, the larger R_b would play an insignificant role in determining NF_{min} .

The minimum noise figure NF_{min} versus VDD is shown in Fig. 11. NF_{min} is sharply increased towards the weak inversion region, and this trend is consistent with that for the conventional bulk MOSFET [16]. Moreover, our experimental results show that NF_{min} has less temperature dependence in the low VDD regime. As shown in Fig. 10, in the low VDD regime, since the noise contribution of S_{iRb} to the output noise current for each temperature is not significant, R_b would have little effect on the temperature dependence of NF_{min} .

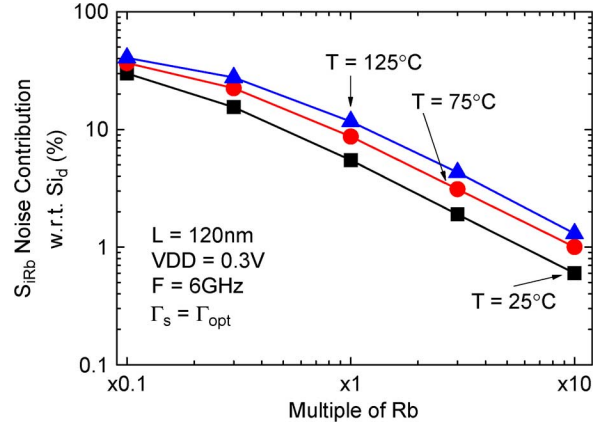


Fig. 10. Sensitivity analysis of the body resistance with respect to its noise contribution.

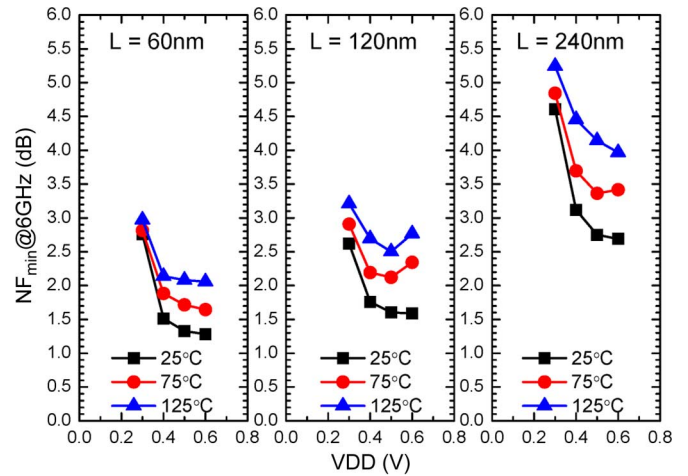


Fig. 11. NF_{min} as a function of VDD at different temperatures for various channel length devices. (Data normalized with respect to their corresponding values at $T = 25^\circ\text{C}$.)

V. CONCLUSIONS

We have investigated the temperature dependences of RF small-signal and noise behaviors for the DT MOSFET. In the low VDD regime, since g_m tends to increase with temperature, f_t would have a positive temperature coefficient. On the other hand, due to the less temperature-dependent behavior of α_{DT} and $\sqrt{R_{ds}/R_i}$, f_{max} is found to increase with temperature as well. Moreover, the body-related parasitics and the series resistances are found to have more impact on f_{max} than f_t .

In the low VDD regime, the channel noise S_{id} has a positive temperature coefficient due to larger g_{d0} at higher temperature. In addition, compared to S_{id} , the much higher g_m^2 toward the weaker inversion region can cause R_n to have a negative temperature coefficient. Finally, it shows that, in the low VDD regime, the large R_b would have little impact on the temperature dependence of NF_{min} .

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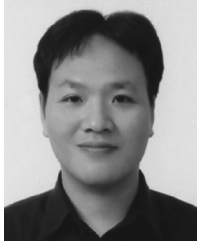
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